

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Tetsuo SHIMOMURA et al.
Appl. No. : 10/598,717
Filed : September 8, 2006
For : POLISHING PAD AND
SEMICONDUCTOR DEVICE
MANUFACTURING METHOD
Examiner : Alvin J. Grant
Group Art Unit : 3723

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Katsuhiro Arai, Reg.43,315

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed July 27, 2007, please reconsider the present application in light of the following amendments and comments.

Amendments to the Claims are reflected in the listing of claims which begin on page 2 of this paper

Remarks/Arguments begin on page 7 of this paper.